



IFW

PATENT
Customer No. 22,852
Attorney Docket No. 3180.0342

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
NOBUHIRO KOMINE)
Application No.: 10/721,903) Group Art Unit: 2851
Filed: November 26, 2003) Examiner: D. Rutledge
For: RETICLE, EXPOSURE) Confirmation No.: 9102
MONITORING METHOD,)
EXPOSURE METHOD AND)
MANUFACTURING METHOD)
FOR SEMICONDUCTOR DEVICE)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

SUPPLEMENTAL AMENDMENT

This Supplemental Amendment is being filed in addition to the Amendment filed on August 10, 2005.

Amendments to the Specification are included in this paper.

Remarks/Arguments follow the amendment sections of this paper.

Attachments to this paper include a copy of Fig. 9 and marked-up versions Figs. 10 and 11.